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PHOTORESIST RECIRCULATION
AND VISCOSITY CONTROL FOR
DIP COATING APPLICATIONS

ABSTRACT OF THE DISCLOSURE

A method of performing dip coating of a layer of a resist material on a surface of a substrate, comprising steps of:

(a) providing a dip coating vessel having an interior space containing a dip coating liquid comprising a solution of the resist material in a solvent, the dip coating vessel being open at the top thereof;

(b) providing a substrate having a surface, immersing the substrate in the dip coating liquid in the vessel *via* the open top, and withdrawing the substrate from the vessel *via* the open top thereof, thereby forming a layer of resist material on the surface; and

(c) monitoring and maintaining the viscosity of the dip coating liquid supplied to the dip coating vessel at a predetermined value.

Also disclosed is an apparatus for performing the method.